

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In Re Application of:

Robert David Allen et al.	Examiner:	John S.Y. Chu
Serial No.: 10/729,452	Group Art Unit:	1795
Filing Date: December 4, 2003	Confirmation No:	2060
Title: METHOD FOR PATTERNING A LOW ACTIVATION ENERGY PHOTORESIST		

**AMENDMENT UNDER 37 CFR 1.111**  
**AND REQUEST FOR EXTENSION OF TIME**

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

This is in response to the Office Action mailed from the PTO on October 22, 2008. A one-month extension of time is requested, and the fee therefor accompanies this response. Please amend the application as indicated herein.

The *Listing of the Claims* begins on page 2 of this document. Amendments to the claims are reflected therein. With this amendment, claim 1 has been amended.

*Remarks* begin on page 11 of this document.